

















Impact of Ethernet Overhead on Delay

	UDP	VPN (UDP)	OPC (TCP)	DeviceNet
Delay Average (ms)	0.33	1.21	1.48	0.3-1.2
Delay Variation (3σ) (ms)	0.09	0.49	2.43	0.005-0.2
Minimum Network Contribution (ms)	0.035	0.035	0.035	0.188
% of Delay Due to Network	11%	3%	2%	63%

Application layer protocols contribute greater delays.

Delay and delay variability can reduce data quality by causing inconsistent availability and rendering time-stamps to be inaccurate.

Ideally, performance improvement of application protocols need to be optimized and data must be time-stamped at point of measurement for optimal accuracy.

Need to implement standards for time synchronization (SEMI E148) and follow data quality guidelines on *where to time-stamp* and how to *minimize delay variability* in end-to-end communication.

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Summary of Observations

EDA end-to-end delay is largely in the higher levels of software at the nodes when networks are not saturated.

Network congestion (and delay) is generally not an issue

for the EDA data collection scenarios examined.

•100 Mbps switched Ethernet network failure would occur with about 1400 EDA nodes transmitting 830 Bytes at 10Hz each

Use switched rather than hub-based networks for EDA

Data in hub-based networks are susceptible to:

- Low determinism and significant delays
- Especially during network traffic bursts

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Further Information

Contacts:

Ya-Shian Li-Baboud: <u>ya-shian.li-baboud@nist.gov</u> James Moyne: <u>moyne@umich.edu</u>

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